

AMENDMENTS TO THE CLAIMS

1. – 17. (Cancelled)

18. (Currently Amended) A method of manufacturing a strain element, comprising the steps of:

forming a coating film of titanium or a titanium compound on a surface of a cylindrical mold;

shaping the coating film, which has been formed on the surface of the cylindrical mold, into a coil;

forming a crystal film of a strain element having a property of a piezoelectric inverse effect by hydrothermal synthesis on the coating film shaped into the coil; and

removing the strain element from the cylindrical mold.

19. (Currently Amended) A method of manufacturing the strain element according to claim 18, further comprising the step of forming the crystal film of the strain element having the property of the piezoelectric inverse effect by the hydrothermal synthesis on an inner circumferential surface of the strain element removed from the cylindrical mold.

20. (Currently Amended) A method of manufacturing the strain element according to claim 18, further comprising:

the step of forming the coating film of titanium or the titanium compound on an outer circumferential surface of the strain element removed from the cylindrical mold; and

forming [[a]] the crystal film of [[a]] the strain element having the property of the piezoelectric inverse effect by the hydrothermal synthesis on the coating film formed on the outer circumferential surface of the strain element.

21. – 25. (Cancelled).

26. (Currently Amended) A method of manufacturing [[a]] the strain element according to claim 19, further comprising:

[[a]] the step of forming [[a]] the coating film of titanium or [[a]] the titanium compound on an outer circumferential surface of the strain element removed from the cylindrical mold; and

forming [[a]] the crystal film of [[a]] the strain element having the property of the piezoelectric inverse effect by the hydrothermal synthesis on the coating film formed on the outer circumferential surface of the strain element.

27. – 30. (Cancelled).